surface 3 of which secondary electron emission efficiency is high.

Next, the cathode electrode 4 and the anode electrode 5 were formed on both faces of the insulating substrate 1 having the channel 2. It was formed by obliquely evaporating aluminum by the vacuum evaporation method. Thus, the channel plate was successfully produced (see FIG. 4D).

The channel plate using the nanoholes formed by the anodic oxidation has very narrow spacing between the pores so that it is the plate of higher resolution than conventional ones.